Receipt date: 07/12/2006

Docket No.

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MAIL STOP PCT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF:

Yasuo MATSUKI, et al.

JUL 1 2 2006

SERIAL NO:

10/575,478

GAU:

FILED:

April 12, 2006

EXAMINER:

FOR:

COMPOSITION FOR FORMING SILICON-COBALT FILM, SILICON-COBALT FILM AND METHOD FOR

FORMING SAME

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97

COMMISSIONER FOR PATENTS ALEXANDRIA, VIRGINIA 22313

SIR:

Applicant(s) wish to disclose the following information.

REFERENCES

- The applicant(s) wish to make of record the references listed on the attached form PTO-1449. Copies of the listed references are attached, where required, as are either statements of relevancy or any readily available English translations of pertinent portions of any non-English language references.
- A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

RELATED CASES

- Attached is a list of applicant's pending application(s), published application(s) or issued patent(s) which may be related to the present application. In accordance with the waiver of 37 CFR 1.98 dated September 21, 2004, copies of the cited pending applications are not provided. Cited published and/or issued patents, if any, are listed on the attached PTO form 1449.
- ☐ A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

CERTIFICATION

- ☐ Each item of information contained in this information disclosure statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.
- □ No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

DEPOSIT ACCOUNT

Please charge any additional fees for the papers being filed herewith and for which no check or credit card payment is enclosed herewith, or credit any overpayment to deposit account number <u>15-0030</u>. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

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Tel. (703) 413-3000 Fax. (703) 413-2220 (OSMMN 05/03) Receipt date: 07/12/2006 SHEET OF 1 TRADENAM SERIAL NO. ATTY DOCKET NO. U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE Form PTO 1449 (Modified) 288992US0PCT 10/575,478 **APPLICANT** LIST OF REFERENCES CITED BY APPLICANT Yasuo MATSUKI, et al. **GROUP FILING DATE** April 12, 2006 **U.S. PATENT DOCUMENTS** SUB FILING DATE **EXAMINER** DOCUMENT DATE **CLASS** NAME INITIAL NUMBER **CLASS** IF APPROPRIATE AA AB AC AD ΑE AF AG AΗ ΑI ΑJ ΑK AL ΑM ΑN FOREIGN PATENT DOCUMENTS TRANSLATION DOCUMENT DATE COUNTRY NUMBER YES NO NO ΑO 4-53512 02/21/92 JP NO 05/30/78 JP (with English translation) AP 53-60171 WO (with English abstract & equivalent of NO AQ 1999/022411 05/06/99 US6506321) WO (with English abstract & equivalent of NO 10/05/00 AR 2000/059040 US6514801) NO JP (with Computer generated translation) AS 3382743 12/20/02 JP (with Computer generated translation & NO 02/20/92 ΑT 4-53132 equivalent of JP2980645) ΑU ΑV OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.) SADOH, Taizoh et al., "High-Performance MOS Tunneling Cathode with CoSi2 Gate Electrode", Jpn. J. Appl. Phys., Vol. 40, AW Part 1, No. 4B, Pages 2775-2778, 2001. ZAIMA, Shigeaki et al., "Formation of silicide at metal/silicon interface and low-resistivity contacts", Applied Physics, Vol. 63, AX No. 11, Pages 1093-1105, 1994. (with English abstract) AY ΑZ Additional References sheet(s) attached

*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in

Examiner

/Shamim Ahmed/ (02/23/2009)

conformance and not considered. Include copy of this form with next communication to applicant.

Date Considered

02/23/2009